

1. Record Nr.	UNINA9910809581903321
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Titolo	Electrochemical micromachining for nanofabrication, MEMS and nanotechnology / / Bijoy Bhattacharyya
Pubbl/distr/stampa	Amsterdam, [Netherlands] : , : William Andrew, , 2015 ©2015
Descrizione fisica	1 online resource (297 p.)
Collana	Micro & Nano Technologies Series
Disciplina	671.35
Soggetti	Micromachining Nanotechnology Microelectromechanical systems
Lingua di pubblicazione	Inglese
Formato	Materiale a stampa
Livello bibliografico	Monografia
Note generali	Description based upon print version of record.
Nota di bibliografia	Includes bibliographical references at the end of each chapters and index.
Nota di contenuto	Front Cover; Electrochemical Micromachining for Nanofabrication, MEMS and Nanotechnology; Copyright; Dedication; Contents; About the Author; Foreword; Preface; Acknowledgment; Symbols; CHAPTER 1 - INTRODUCTION; 1.1 MICROMACHINING AND NANOFABRICATION; 1.2 MEMS AND MICROSYSTEMS; 1.3 CONDITIONS FOR MICROMACHINING AND NANOFABRICATION; 1.4 TYPES OF MICROMACHINING PROCESSES; 1.5 ELECTROCHEMICAL MICROMACHINING; 1.6 ELECTROCHEMICAL TECHNOLOGY FOR MICROSYSTEMS AND NANOFABRICATION; REFERENCES; CHAPTER 2 - ELECTROCHEMICAL MACHINING: MACRO TO MICRO; INTRODUCTION; 2.1 BACKGROUND OF ECM 2.2 FUNDAMENTALS OF ANODIC DISSOLUTION2.3 IMPORTANT INFLUENCING FACTORS OF ECM FOR MICROMACHINING; 2.4 EMM: PRESENT STATUS; REFERENCES; CHAPTER 3 - PRINCIPLE OF MATERIAL REMOVAL IN ELECTROCHEMICAL MICROMACHINING; 3.1 MECHANISM OF MATERIAL REMOVAL; 3.2 EQUIVALENT ELECTRICAL CIRCUIT FOR EMM; 3.3 MRR MODEL; REFERENCES; CHAPTER 4 - TYPES OF EMM; INTRODUCTION; 4.1 THROUGH-MASK EMM; 4.2 MASKLESS EMM; 4.3 THREE-DIMENSIONAL EMM; REFERENCES; CHAPTER 5 - ELECTROCHEMICAL MICROMACHINING SETUP; 5.1 DETAILS OF EMM SETUP; 5.2 CURRENT STATUS OF DEVELOPMENTS IN EMM SETUP; 5.3 IEG

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